IN THE CLAIMS

1. (Currently amended) A nonvolatile semiconductor memory device comprising:

a substrate;

a plurality of sectors on the substrate;

<u>a sector on a substrate, the each</u> sector comprising <u>including</u> memory cell transistors arranged in a cell array block and decoder transistors in a column decoder block;

wherein the transistors in the cell array block and column decoder block in each sector share a common bulk region, wherein the common bulk region is formed on the substrate and is connected to a bulk driver provided in each of the sectors, each said, the bulk driver configured to commonly apply a bulk voltage to the common bulk region of the sector; and

wherein said semiconductor memory device is configured to electrically erase all the memory cell transistors in a the sector together.

- 2. (Original) A nonvolatile semiconductor memory device according to claim 1, wherein the semiconductor memory device is a NOR-type memory device.
- 3. (Original) A nonvolatile semiconductor memory device according to claim 1, further comprising a write driver and a sense amplifier.
- 4. (Original) A nonvolatile semiconductor memory device according to claim 3, wherein the write driver and sense amplifier are configured to be placed in a state of high impedance during an erase operation to avoid influencing circuit operation during the erase operation.
- 5. (Original) A sector structure of a nonvolatile semiconductor memory, said sector structure comprising:
- a plurality of memory cell transistors arranged in a cell array block; and a plurality of decoder transistors arranged in a column decoder block, wherein said memory cell transistors and decoder transistors are arranged on a common bulk region.
- 6. (Original) A sector structure of a nonvolatile semiconductor memory according to claim 5, wherein an erase operation is configured to erase all of the transistors in the sector simultaneously.

- 7. (Original) A sector structure of a nonvolatile semiconductor memory according to claim 5, said sector structure further comprising:
- a plurality of word lines arranged in the cell array block, each word line being connected to a plurality of cell gates;
- a plurality of bit lines arranged in the cell array block, each bit line being connected to a plurality of memory cell drains;
 - a plurality of common data lines connected to the bit lines;
- a plurality of write drivers, each connected to a respective one of the common data lines; and
- a plurality of sense amplifiers, each connected to a respective one of the common data lines.
- 8. (Original) A sector structure of a nonvolatile semiconductor memory according to claim 7, wherein each write driver and sense amplifier is configured to be placed in a state of high impedance during an erase operation.
- 9. (Original) A sector structure of a nonvolatile semiconductor memory according to claim 5, wherein said sector structure is configured to provide 64 Kbytes of memory.
- 10. (Currently amended) A <u>sector of a</u> nonvolatile semiconductor memory device with a plurality of sectors, each sector comprising:
- a cell array block eomprising including a plurality of word lines, a plurality of bit lines, and a plurality of memory cell transistors having gates and drains, each gate being connected to a corresponding word line out of the plurality of word lines, each drain being connected to a corresponding bit line out of the plurality of bit lines;
- a source line driver commonly connected to a source of each of the plurality of memory cell transistors and configured to apply a source voltage;
- a column decoder block comprising a plurality of column decoder transistors, each column decoder transistor connected to a corresponding bit line out of the plurality of bit lines and a common data line configured to select one bit line out of the plurality of bit lines; and

a common bulk region arranged in each the sector and formed immediately adjacent to a substrate region, wherein the plurality of memory cell transistors and the plurality of column decoder transistors in each the sector share the common bulk region; and

a bulk driver provided in each of the sectors, each said the bulk driver configured to commonly apply a bulk voltage to the common bulk region of that the sector.

- 11. (Currently amended) A nonvolatile semiconductor memory device according to claim The sector of claim 10, wherein the nonvolatile semiconductor memory device is a NOR-type flash EEPROM.
- 12. (Currently amended) A nonvolatile semiconductor memory device according to The sector of claim 10, wherein the bulk region is a pocket P-well.
- 13. (Currently amended) A nonvolatile semiconductor memory device according to The sector of claim 10, further comprising a plurality of write drivers and sense amplifiers, a write driver and a sense amplifier, wherein each the common data line is connected to a corresponding one of the write drivers and a corresponding one of the sense amplifiers. the write driver and the sense amplifier.
- 14. (Currently amended) A nonvolatile semiconductor memory device according to The sector of claim 13, wherein the write drivers driver and the sense amplifiers are each amplifier configured to be placed in a state of high impedance during an erase operation.
- 15. (Currently amended) A nonvolatile semiconductor memory device comprising:

a substrate;

a plurality of sector units, each unit, the sector unit comprising including a common bulk region, the bulk region being formed on the substrate and connected to a bulk driver, and wherein each the sector unit is configured to be electrically erasable in response to an erase signal; and a plurality of memory cell transistors and transistors of a column decoder arranged in the common bulk region of each the sector unit and configured to commonly receive a bulk voltage.

Page 5 of 13

- 16. (Currently amended) A nonvolatile semiconductor memory device according to claim 15, wherein each the sector unit further comprises a bulk driver configured to supply a bulk voltage to the common bulk region.
- 17. (Original) A nonvolatile semiconductor memory device according to claim 15, wherein said plurality of memory cell transistors are arranged in a cell array block, wherein said plurality of column decoder transistors are arranged in a column decoder block, and wherein said cell array block and said column decoder block are both arranged on the common bulk region.
- 18. (Currently amended) A method of forming a bulk region of a nonvolatile semiconductor device, said method comprising:

forming a bulk region for memory cell transistors provided in a cell array block of the nonvolatile semiconductor memory device, wherein the memory cell transistors of the cell array block is are arranged in an (M x N) array with M and N both at least equal to two; and

forming a bulk region for decoder transistors of a column decoder in the bulk region for the memory cell transistors of the cell array block, wherein the column decoder transistors of the column decoder is are arranged in a $(P \times N)$ within a $(N \times N)$ array with P at least equal to one adjacent to the cell array block.

- 19. (Original) A method of forming a bulk region of a nonvolatile semiconductor device, according to claim 18, further comprising configuring the bulk regions for the memory cell transistors and decoder transistors to receive a common bulk signal during an erase operation.
- 20. (Original) A method of forming a bulk region of a nonvolatile semiconductor device, according to claim 18, wherein said memory cell transistors and said decoder transistors are configured to be simultaneously erased with each other during an erase operation.
- 21. (Withdrawn) A nonvolatile semiconductor memory device comprising: a plurality of sectors, wherein each sector further comprises a plurality of memory cell transistors arranged in a (M x N) array having M word lines and N bit lines where M is at least equal to two; wherein each sector further comprises N decoder transistors corresponding

to one of the N bit lines, wherein the plurality of memory cell transistors and the N decoder transistors share a common bulk region, and wherein the semiconductor memory device is configured to electrically erase the plurality of memory cell transistors simultaneously.

22. (Withdrawn) A sector structure of a nonvolatile semiconductor memory, the sector structure comprising:

a plurality of memory cell transistors arranged in a $(M \times N)$ array where M is at least equal to two; and

N decoder transistors, wherein the plurality of memory cell transistors and the N decoder transistors are arranged on a common bulk region.

- 23. (Withdrawn) A nonvolatile semiconductor memory device, comprising:
 a (M x N) array, wherein M is at least equal to two, comprising a plurality of memory
 cell transistors having gates and drains, each gate connected to a corresponding one of M
 word lines, each drain connected to a corresponding one of N bit lines;
- a source line driver commonly connected to a source of each of the plurality of memory cell transistors;
- a column decoder comprising N column decoder transistors connected between the N bit lines and a common data line;
- a common bulk region, wherein the plurality of memory cell transistors and the N column decoder transistors share the common bulk region; and
- a bulk driver configured to commonly apply a bulk voltage to the common bulk region.
 - 24. (Withdrawn) A nonvolatile semiconductor memory device comprising:
- a plurality of sector units, each sector unit comprising a common bulk region wherein each sector unit is configured to be electrically erasable in response to an erase signal, wherein each of the plurality of sector units further comprises a (M x N) array of memory cell transistors arranged in the common bulk region of each sector unit and configured to commonly receive a bulk voltage, wherein M is at least equal to two, and wherein each of the plurality of sector units further comprises a (1 x N) array of column decoder transistors arranged in the common bulk region of each sector unit and configured to commonly receive the bulk voltage.

25. (Withdrawn) A method of forming a bulk region of a nonvolatile semiconductor device comprising:

forming a first bulk region for a plurality of memory cell transistors provided in a (M x N) array, wherein M is at least equal to two; and

forming a second bulk region for N column decoder transistors, wherein the first and the second bulk regions are integrally connected.

- 26. (Currently amended) The device of claim 1, wherein the cell array block and the column decoder block of each sector share a plurality of word lines and a plurality of bit lines.
- 27. (Currently amended) The device of claim 17, wherein the <u>plurality of memory cell transistors of the cell array block is are arranged in a (M x N) array and the <u>plurality of column decoder transistors of the column decoder block is are arranged in a (P x N) within a (N x N) array adjacent to the cell array block, where M and N are at least equal to two and P is at least equal to one.</u></u>